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## III-V Optoelectronics and Semiconductor Process Technology

Guest Editors:

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**Prof. Dr. Hao-Chung Kuo**

**Prof. Dr. Yi-Jen Chiu**

Deadline for manuscript  
submissions:  
**closed (31 July 2024)**

### Message from the Guest Editors

Dear Colleagues,

The Special Issue "**III-V Optoelectronics and Semiconductor Process Technology**" in the Journal ***Micromachines*** invites high-quality contributions from both academia and industry. The topics covered include the epitaxial growth and fabrication of III-V semiconductors, device design and characterization, novel device concepts, and process technology for III-V-based devices. The Special Issue also covers the use of III-V materials in various applications, such as LEDs, lasers, photovoltaic cells, and sensors.

We look forward to receiving your submissions to this Special Issue.



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**Special** Issue



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### **Prof. Dr. Nam-Trung Nguyen**

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## Message from the Editor-in-Chief

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